

	Type	L #	Hits	Search Text	DBs	Time Stamp
1	BRS	L1	2610	359/224,290-292,295,298,350,847.ccl s.	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 17:44
2	BRS	L2	1647317	@pd>=20030301	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 17:45
3	BRS	L4	65120	electro-optic\$6 or (electro adj3 optic\$6) or electrooptic\$6	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 17:46
4	BRS	L5	407921	membrane\$2	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 17:46
5	BRS	L6	429183	interference\$2 or interferometric\$5	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 17:46
6	BRS	L7	783072	silicon	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 17:47
7	BRS	L8	107841	single near3 crystal\$7	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 17:51
8	BRS	L9	54383	7 and 8	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 17:50

09/841,332

	Type	L #	Hits	Search Text	DBs	Time Stamp
9	BRS	L10	669	4 and 5 and 6	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 17:50
10	BRS	L11	73	10 and 9	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 17:50
11	BRS	L12	34873	(single near3 crystal\$7) near2 silicon\$5	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 17:51
12	BRS	L13	34	11 and 12	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 17:52
13	BRS	L3	329	1 and 2	USPAT; US-PGPUB ; EPO; JPO; DERWENT ; IBM_TDB	2004/01 /30 18:10

	D cument ID	<input checked="" type="checkbox"/> U S P A T	Issue Date	Pa ge s	Title	Current OR	Current XRef
1	US 20030022393 A1	<input checked="" type="checkbox"/> U S P A T	20030 130	47	Array cytometry	436/518	
2	US 20020141036 A1	<input checked="" type="checkbox"/> U S P A T	20021 003	25	Device for use with a micro-electro-mechanical system (MEMS) optical device and a method of manufacture therefor	359/291	359/290; 359/292
3	US 6654157 B2	<input checked="" type="checkbox"/> U S P A T	20031 125	21	Micromechanical optical switch	359/291	359/578
4	US 6618184 B2	<input checked="" type="checkbox"/> U S P A T	20030 909	25	Device for use with a micro-electro-mechanical system (MEMS) optical device and a method of manufacture therefor	359/291	359/214; 359/230; 359/290
5	US 6611366 B2	<input checked="" type="checkbox"/> U S P A T	20030 826	19	Micromechanical optical switch	359/291	359/578; 359/583; 385/16
6	US 4234361 A	<input checked="" type="checkbox"/> U S P A T	19801 118	11	Process for producing an electrostatically deformable thin silicon membranes utilizing a two-stage diffusion step to form an etchant resistant layer	438/566	257/429; 257/E21.14 6; 257/E21.22 3; 257/E21.22 8; 29/621.1; 338/2; 338/4; 438/694; 438/924; 438/974
7	US 4203128 A	<input checked="" type="checkbox"/> U S P A T	19800 513	11	Electrostatically deformable thin silicon membranes	331/156	137/831; 257/415; 257/531; 257/E29.32 4; 257/E45.00 1; 361/281; 361/283.4; 73/77
8	US 6407851 B1	<input checked="" type="checkbox"/> U S P A T	20020 618	20	Micromechanical optical switch	359/291	359/578; 359/583; 359/589; 385/16; 385/47; 398/52